



Match & Return

5010-14014

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.

Serial No.: 09/461,432

Filed: December 16, 1999

For: VACUUM PROCESSING APPARATUS AND OPERATING METHOD THEREFOR

Group: 3749

Examiner: S. Gravini

Allowed: December 7, 2000

Batch No.: W11

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OK to enter

SMA

AMENDMENT UNDER 37 CFR 1.312

Assistant Commissioner for Patents

Box Issue Fee

Washington, D.C. 20231

January 18, 2001

Sir:

Please amend the above-identified application, subsequent to issuance of the Notice of Allowance mailed December 7, 2000, as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

1. (Amended) A method of using a conveyor system for processing substrates in plural vacuum processing chamber installation portions, the conveyor system including:
- an atmospheric loader, exposed to the air;
 - a vacuum loader; and
 - a lock chamber, having an atmospheric loader side

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